



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 10/733,201  
Filing Date ..... December 9, 2003  
Confirmation No. .... 5994  
Inventor ..... Garo J. Derderian et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 1762  
Examiner ..... Kelly M. Stouffer  
Attorney's Docket No. .... MI22-2402  
Customer No. .... 021567  
Title: Atomic Layer Deposition Method of Depositing an Oxide on a  
Substrate

**RESPONSE TO MAY 14, 2007 OFFICE ACTION**

To: Mail Stop Amendment  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**VIA U.S. POSTAL SERVICE**

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)  
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601 West First Avenue, Suite 1300  
Spokane, WA 99201-3828

Responsive to the Office Action dated May 14, 2007, Applicant  
amends and remarks as follows:

**AMENDMENTS**

08/15/2007 SSESHE1 00000015 10733201

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